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INFORMATION DISCLOSURE STATEMENT BY APPLICANT

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Sheet

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Complete if Known

Application Number	09/905,718
Filing Date	May 16, 2002
First Named Inventor	Watts et al.
Group Art Unit	1762
Examiner Name	Bernard D. Pianalto
Attorney Docket Number	PA27/UTS-26-03q12

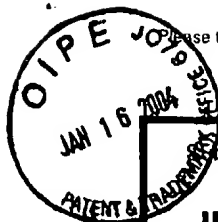
U.S. PATENT DOCUMENTS

Examiner Initials*	Cita No. ¹	U.S. Patent Document		Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number	Kind Code ² (if known)			
BP	A1	3,807,027		Heisler	04-30-1974	
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Examiner Signature	Pianalto				Date Considered	7-29-04

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Examiner Name	Bernard D. Pinalto
Attorney Docket Number	PA27/UTS-26-03q12

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[Signature]	A35	5,633,505		Chung et al.	05-27-1997	
	A36	5,723,176		Keyworth et al.	03-03-1998	
	A37	5,724,145		Kondo et al.	03-03-1998	
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	A40	5,760,500		Kondo et al.	06-02-1998	
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	A45	5,804,474		Sakaki et al.	09-08-1998	
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	A67	6,218,316		Marsh	04-17-2001	
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	A69	6,245,213		Olsson et al.	06-12-2001	
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Signature

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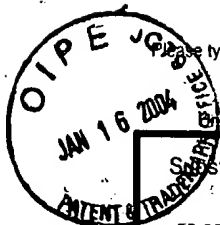
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Substitute for form 1449B/PTO				Complete if Known	
INFORMATION DISCLOSURE STATEMENT BY APPLICANT (use as many sheets as necessary)				Application Number	09/905,718
				Filing Date	May 16, 2002
				First Named Inventor	Watts et al.
				Group Art Unit	1762
				Examiner Name	Bernard D. Pianalto
				Attorney Docket Number	PA27/UTS-26-03q12
Sheet	4	of	9		

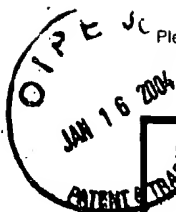
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Examiner Initials*	Cite No.	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
Bl	A90	STEWART, "A Platform with Six Degrees of Freedom," Proc. of Inst. Mech. Engrs., 1965, pp. 371-378, vol. 180 pt. 1, no. 15. (No month avail.)	
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Examiner Signature	<i>Pianalto</i>	Date Considered	7-29-04
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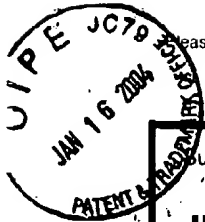
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Bl	A101	ARAI et al., "Calibration and Basic Motion of a Micro Hand Module," Proc. of IEEE, 1993, pp. 1660-1665. (no month avail.)	
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	A111	CHOU et al., "Imprint Lithography with 25-Nanometer Resolution," Science, Apr. 5, 1996, pp. 85-87, vol. 272.	

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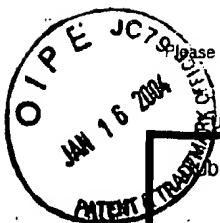
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Bl	A112	HOWELL et al., "Loop-Closure Theory for the Analysis and Synthesis of Compliant Mechanisms," Journal of Mechanical Design, March 1996, pp. 121-125, vol. 118.		
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	A121	KANETOMO et al., "Robot for Use in Ultrahigh Vacuum," Solid State Tech., August 1997, pp. 63-64, 69-72.		
	A122	GOLDFARB et al., "Compliant Micromanipulator Design for Scaled Bilateral Telemanipulation of Small-Scale Environments," Proc. of the ASME, Dynamic Systems and Control Div., 1998, pp. 213-218, vol. 64. (no match avail.)		

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	A133	OHYA et al., "Development of 3-DOF Finger Module for Micro Manipulation," Proc. of the 1999 IEEE/RSJ, Intl. Conf. on Intelligent Robots and Systems, 1999, pp. 894-899.	

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				Application Number	09/905,718
				Filing Date	May 16, 2002
				First Named Inventor	Watts et al.
				Group Art Unit	1762
				Examiner Name	Bernard D. Pianalto
				Attorney Docket Number	PA27/UTS-26-03q12
Sheet	8	of	9		

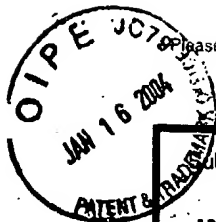
OTHER PRIOR ART - NON PATENT LITERATURE DOCUMENTS			
Examiner Initials*	Cite No.	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
BP	A134	TANIKAWA et al., "Development of Small-Sized 3 DOF Finger Moldule in Micro Hand for Micro Manipulation," Proc. of the IEEE/RSJ, Intl. Conf. on Intelligent Robots and Systems, 1999, pp. 876-881. (no month avail.)	
	A135	COLBURN. et al., "Step and Flash Imprint Lithography: A New Approach to High-Resolution Patterning", Proc. of SPIE, 1999, pp. 379-389, vol. 3676. (no month avail.)	
	A136	Lucas Aerospace, Free-Flex Pivot Catalog, 1999. (no month avail.)	
	A137	GOLDFARB et al., "A Well-Behaved Revolute Flexure Joint for Compliant Mechanism Design," Journal of Mech. Design, Sept. 1999, pp. 424-429, vol. 121.	
	A138	Geodetic Technology, G1000-PC Power Series Specifications, 1999, from www.hexapods.com. (no month avail.)	
	A139	Hexel Corporation, Tornado 2000 System Specifications, 1999, from www.Hexel.com. (no month avail.)	
	A140	Physik Instruments, PI Online-Catalog, 1999, from www. Physikinstrument.com. (no month avail.)	
	A141	CHOU et al., "Lithographically-Induced Self Assembly of Periodic Polymer Micropillar Arrays," Journal of Vacuum Science and Technology, Nov/Dec 1999, pp. 3197-3202, vol. B 17(6).	
	A142	RUCHHOEFT et al., "Patterning Curved Surfaces: Template Generation by Ion Beam Proximity Lithography and Relief Transfer by Step and Flash Imprint Lithography," Journal of Vacuum Science and Technology, 1999, pp. 2965-2982, vol. 17. (no month avail.)	
	A143	Vanderbilt University Office of Transfer Technology, VU 9730 Specifications for Improved Flexure Device; 2001, from www.vanderbilt.com. (no month avail.)	
	A144	STIX, "Getting More from Moore's," Scientific American, 2001, from www.scientificamerican.com. (no month avail.)	

Examiner Signature	<i>B. Pianalto</i>	Date Considered	7-29-04
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Sheet 9 of 9

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OTHER PRIOR ART - NON PATENT LITERATURE DOCUMENTS

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[Handwritten Initials]	A145	CHOI et al., "High Precision Orientation Alignment and Gap Control Stages for Imprint Lithography Processes," U.S. Patent Application 09/698,317, Filed with USPTO on October 27, 2000.	
	A146	SREENIVASAN et al., "High-Resolution Overlay Alignment Methods and Systems for Imprint Lithography," U.S. Patent Application 09/907,512, Filed with USPTO on July 16, 2001.	
	A147	CHOI et al., "Method and System of Automatic Fluid Dispensing for Imprint Lithography Processes," U.S. Patent Application 09/908,455, Filed with USPTO on July 17, 2001	
	A148	WILLSON et al., "Step and Flash Imprint Lithography," U.S. Patent Application 09/908, 765, Filed with USPTO on July 19, 2001.	
	A149	CHOI et al., "Methods for High-Precision Gap and Orientation Sensing Between a Transparent Template and Substrate for Imprint Lithography," U.S. Patent Application 09/920,341, Filed with USPTO on August 1, 2001.	
	A150	Nguyen, A. Q., "Asymmetric Fluid-Structure Dynamics in Nanoscale Imprint Lithography," University of Texas at Austin, August 2001.	
	A151	CHOI et al., "Flexure Based Macro Motion Translation Stage," U.S. Patent Application 09/934,248, Filed with USPTO on Auguts 21, 2001.	
	A152	BAILEY et al., "Template for Room Temperature Low Pressure Micro- and Nano-Imprint Lithography," U.S. Patent Application 09/976,681, Filed with USPTO on October 12, 2001.	
	A153	WATTS et al., "Low Viscosity High Resolution Patterning Material," U.S. Patent Application 10/178,947, Filed with USPTO on June 24, 2002.	

Examiner
Signature

[Handwritten Signature: Pianalto]

Date

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